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Tae-Gon KIM is a professor of Department of Smart Convergence Engineering in Hanyang University ERICA. He is actively engaged in international standardization efforts as the Committee Manager of the ISO TC201/SC9, which is the scanning probe microscopy subcommittee. Additionally, he is actively involved in domestic and international conferences related to semiconductor cleaning, CMP, and surface analysis. He received his Bachelor, Master and PhD from Metallurgy and Material Science and Engineering in 2001, 2003 and 2008 in Hanyang University ERICA, South Korea, respectively. He studied semiconductor cleaning and CMP processes. He was a postdoctoral research fellow in imec and KU Leuven, Belgium in from 2008 to 2010. He was a senior researcher in a scientific advisor of in-line metrology from 2010 to 2019. He was appointed as a professor at Hanyang University ERICA in 2019. In his research career, he has been leading activity on semiconductor cleaning and CMP, advanced film characterization as well as in-line metrology technique for advanced technology node and in-line 3D-AFM technology for 3-dimensional structure characterization such as sidewall characterization of FinFET and Nanowire.